Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	37434	(artifact\$3 or nois\$3 or distort\$4)same(enhanc\$6 or correct\$4 or filter\$3 or adjust\$6)same(imag\$3)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:29
L2	10170	1 same(compar\$6 or correlat\$4 or match\$3 or similar\$4)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:29
Ц3	4504	2 same(scan\$4 or read\$3 or detect\$3 or extract\$3)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:30
L4	708	3 same(film\$3 or photograph\$4 or pictur\$4)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:26
L5	11	4 same(fourier\$4)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:35
L6	5874	(artifact\$3 or nois\$3 or distort\$4)same(enhanc\$6 or correct\$4 or filter\$3 or adjust\$6)same(film\$4)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:29
L7	241	6 same(compar\$6 or correlat\$4 or match\$3 or similar\$4)near10 imag\$4	US-PGPUB; USPAT	OR	ON	2005/06/09 16:29
L8	129	7 same(scan\$4 or read\$3 or detect\$3 or extract\$3)near10(film\$4 or pictur\$3 or photograph\$4)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:31
L9	0	8 same(fourier\$4)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:32
L10	27	8 same(digit\$6)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:35
L11	1	"6615648".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:33
L12	1	"6560729".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L13	1	"6336095".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L14	1	"6336095".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L15	1	"6178253".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L16	1	"5817945".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L17	1	"6178253".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L18	1	"6442301".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L19	1	"6091445".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34

L20	1	"5991010".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L21	1	"5528288".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:34
L22	1	"5528288".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:35
L23	1	"5319719".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:35
L24	179	4 same(digit\$6)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:35
L25	3	24 same(fourier\$4)	US-PGPUB; USPAT	OR	ON	2005/06/09 16:36
L26	1	"6324573".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:36
L27	1	"6285773".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:36
L28	1	"6275592".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:36
L29	1	"6232994".PN.	USPAT; USOCR	OR,	ON	2005/06/09 16:36
L30	1	"6188770".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:37
L31	1	"6188770".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:37
L32	1	"6084971".PN.	USPAT; USOCR	OR	ON	2005/06/09 16:37



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Key: IEEE JNI. = IEEE Journal or Magazine, IEE JNI. = IEE Journal or Magazine, IEEE CNF = IEEE Conference, IEEE STD = IEEE Standard

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